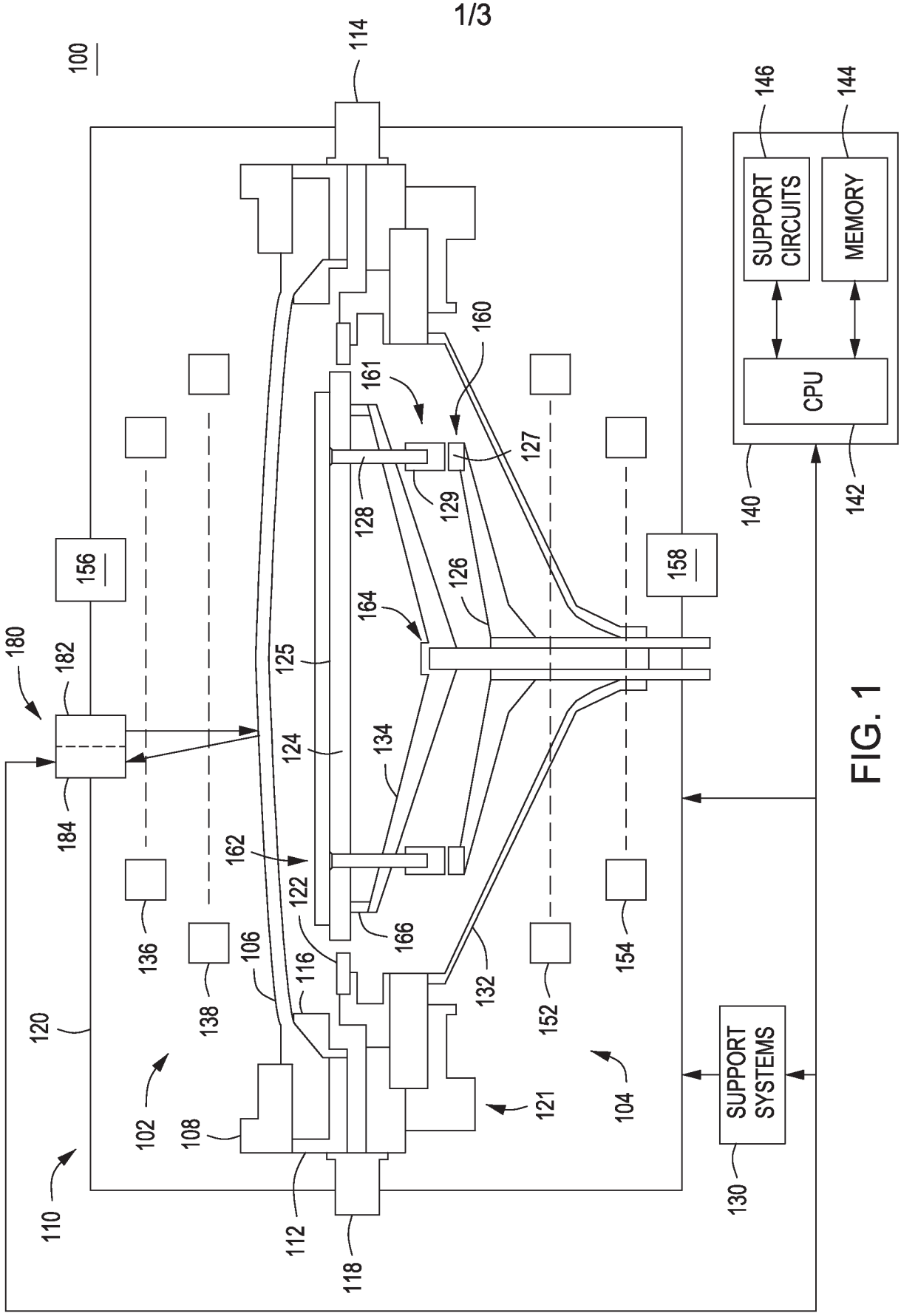

100
114
146
144
SUPPORT CIRCUITS
MEMORY
CPU
140
142
160
161
127
128
129
126
156
158
164
180
182
125
124
134
184
162
122
166
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106
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138
132
152
154
120
102
108
121
104
110
112
118
SUPPORT SYSTEMS
130

FIG. 1

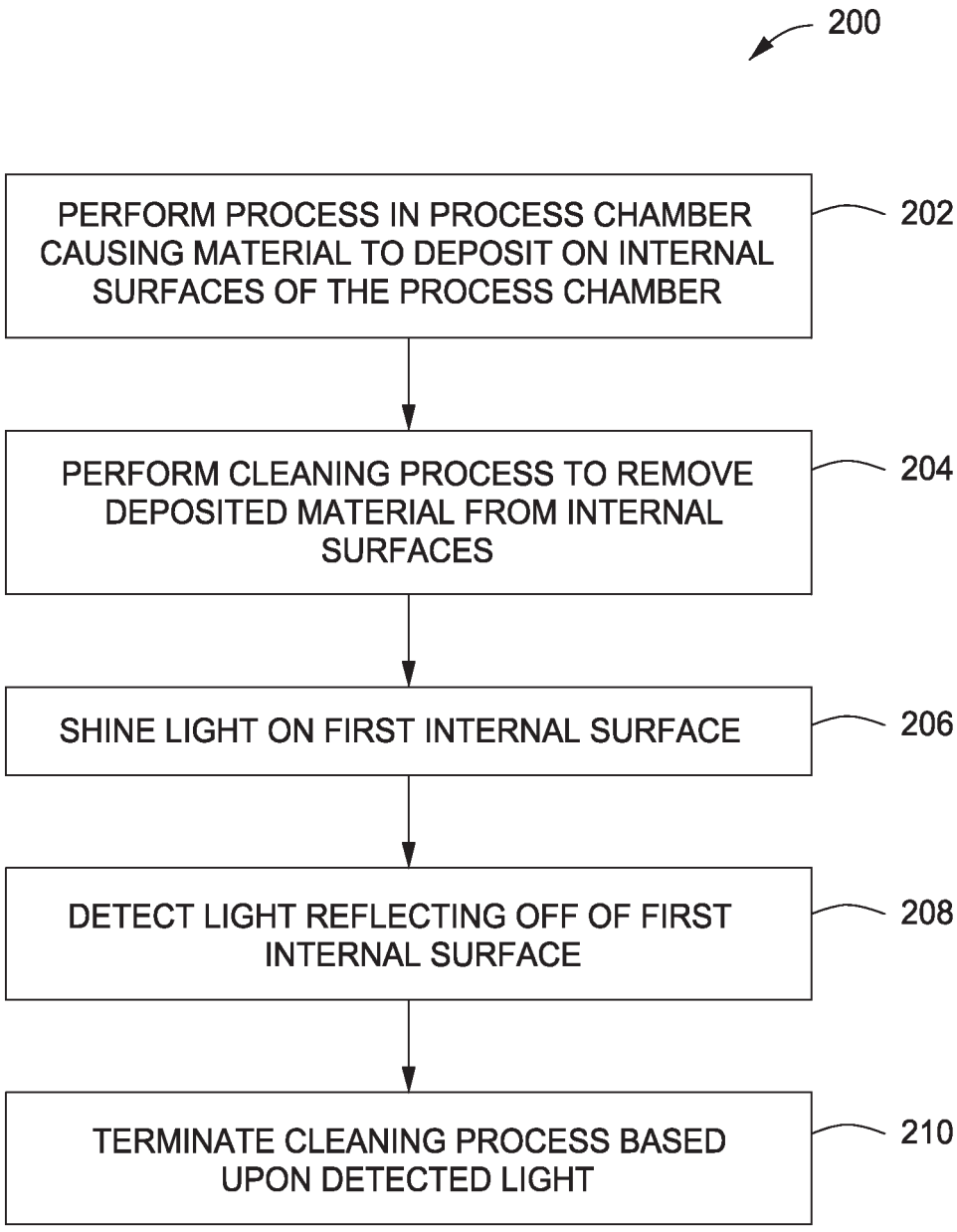

200
PERFORM PROCESS IN PROCESS CHAMBER CAUSING MATERIAL TO DEPOSIT ON INTERNAL SURFACES OF THE PROCESS CHAMBER
202
PERFORM CLEANING PROCESS TO REMOVE DEPOSITED MATERIAL FROM INTERNAL SURFACES
204
SHINE LIGHT ON FIRST INTERNAL SURFACE
206
DETECT LIGHT REFLECTING OFF OF FIRST INTERNAL SURFACE
208
TERMINATE CLEANING PROCESS BASED UPON DETECTED LIGHT
210

FIG. 2

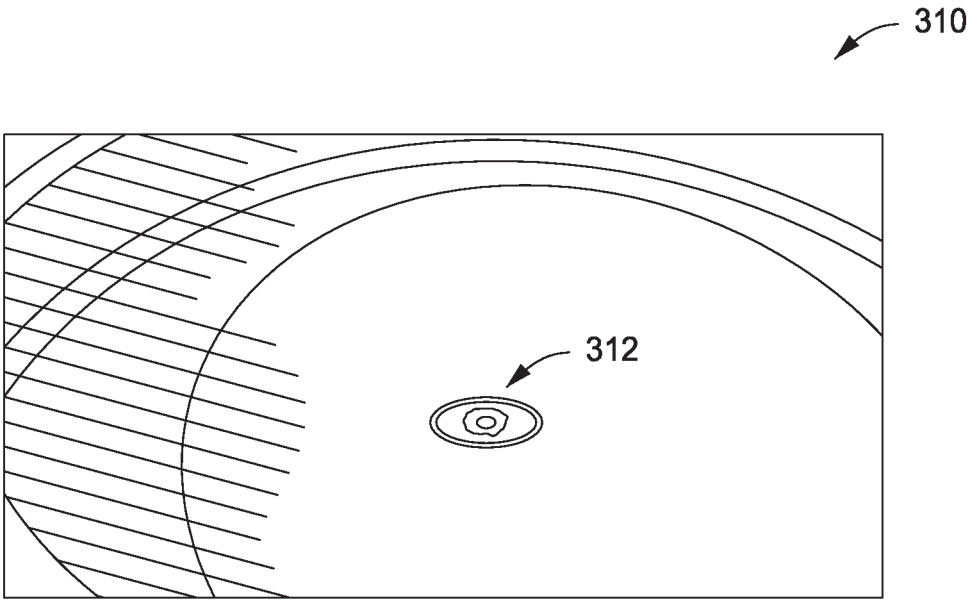


FIG. 3A

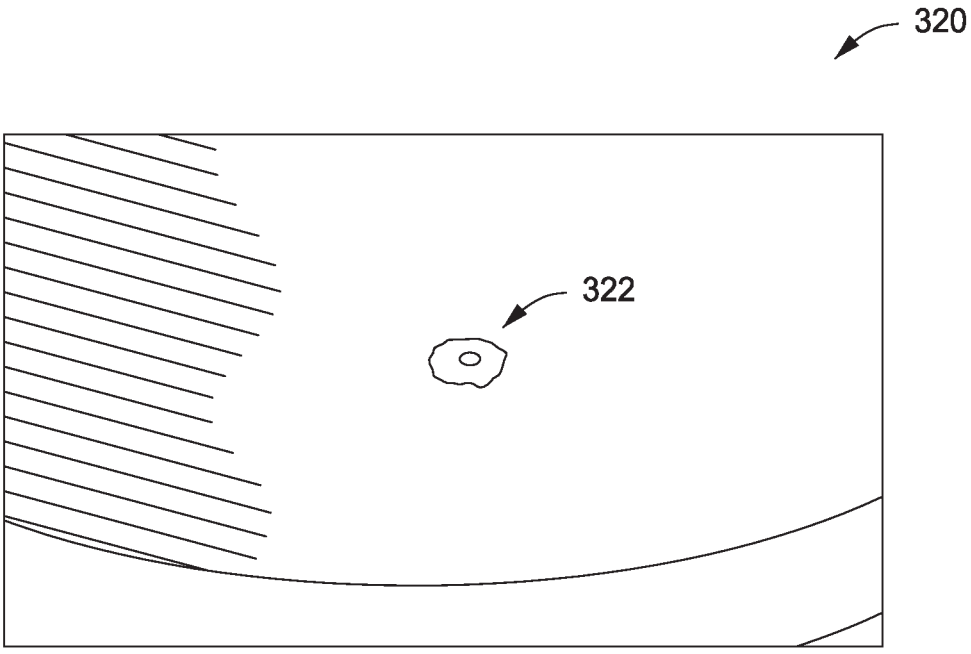


FIG. 3B